What is Claimed Is:

- 1. A material for making an electroconductive pattern, said
 material comprising a support and a light-exposure

 differentiable element, characterized in that said lightexposure differentiable element comprises an outermost layer
 containing a polyanion and a polymer or copolymer of a
 substituted or unsubstituted thiophene, and optionally a
 second layer contiguous with said outermost layer; and wherein
 said outermost layer and/or said optional second layer
 contains a light-sensitive component capable upon exposure of
 changing the removability of the exposed parts of said
 outermost layer relative to the unexposed parts of said
 outermost layer.
 - 2. Material according to claim 1, wherein said polymer of a substituted or unsubstituted thiophene corresponds to formula (II):

$$\mathbb{R}^{1}$$
 \mathbb{Q} \mathbb{R}^{2} $\mathbb{$

- in which n is larger than 1 and each of R^1 and R^2 independently represent hydrogen or an optionally substituted C_{1-4} alkyl group or together represent an optionally substituted cycloalkylene group, preferably an ethylene group, an optionally alkyl-substituted methylene group, an optionally C_{1-12} alkyl- or phenyl-substituted ethylene group, a 1,3-propylene group or a 1,2-cyclohexylene group.
- 3. Material according to claim 1, wherein said polyanion is poly(styrene sulphonate).
 - 4. Material according to claim 1, wherein said outermost layer has a surface resistivity lower than 10 6 $\Omega/\text{square}.$

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- 5. Material according to claim 1, wherein said light-sensitive component capable upon exposure of changing the removability of the exposed parts of said outermost layer relative to the unexposed parts of said outermost layer is a multidiazonium salt or a resin comprising a diazonium salt which reduces the removability of exposed parts of said outermost layer.
- 6. Material according to claim 1, wherein said light-sensitive component capable upon exposure of changing the removability of the exposed parts of said outermost layer relative to the unexposed parts of said outermost layer is a bis(aryldiazosulphonate) salt, a tris(aryldiazosulphonate) salt or a tetrakis(aryldiazosulphonate) salt which reduces the removability of exposed parts of said outermost layer.
 - 7. Material according to claim 1, wherein said light-sensitive component capable upon exposure of changing the removability of the exposed parts of said outermost layer relative to the unexposed parts of said outermost layer is a bis(aryldiazosulphonate) salt, which reduces the removability of exposed parts of said outermost layer, according to formula (I):

$$MO_3S-N=N-Ar-L-Ar-N=N-SO_3M$$
 (I)

where Ar is a substituted or unsubstituted aryl group, L is a divalent linking group, and M is a cation.

8. Material according to claim 6, wherein said

bis(aryldiazosulphonate) salt is selected from the group consisting of

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HO N N N OH

$$\begin{bmatrix} Na^{+} \end{bmatrix}_{2}$$

$$0 = \begin{bmatrix} Na^{+} \end{bmatrix}_{2}$$

$$0 = \begin{bmatrix} Na^{+} \end{bmatrix}_{2}$$
and

- 9. Material according to claim 1, wherein said light-sensitive component capable upon exposure of changing the removability of the exposed parts of said outermost layer relative to the unexposed parts of said outermost layer is a polymer or copolymer of an aryldiazosulphonate which reduces the removability of exposed parts of said outermost layer.
- 10. Material according to claim 9, wherein in said light-exposure differentiable element the weight ratio of said polymer or copolymer of an aryldiazosulphonate to said polymer or copolymer of a substituted or unsubstituted thiophene is between 10:200 and 400:200.
- 11. Material according to claim 1, wherein said light-sensitive component capable upon exposure of changing the removability of the exposed parts of said outermost layer relative to the unexposed parts of said outermost layer is a quinonediazide compound which increases the removability of exposed parts of said outermost layer.
- 12. Material according to claim 1, wherein said support is treated with a corona discharge or a glow discharge.

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- 13. Method of making an electroconductive pattern on a support comprising the steps of:
 - providing a material for making an electroconductive pattern, said material comprising a support and a light-exposure differentiable element, wherein said light-exposure differentiable element comprises an outermost layer containing a polyanion and a polymer or copolymer of a substituted or unsubstituted thiophene, and optionally a second layer contiguous with said outermost layer; and wherein said outermost layer and/or said optional second layer contains a light-sensitive component capable upon exposure of changing the removability of the exposed parts of said outermost layer; relative to the unexposed parts of said outermost layer;
- image-wise exposing said material thereby obtaining a
 differentiation of the removability, optionally with a
 developer, of said exposed and said non-exposed areas of said
 outermost layer;
 - processing said material, optionally with said developer, thereby removing areas of said outermost layer; and optionally treating said material to increase the electroconductivity of said non-removed areas of said outermost layer.
- 14. Method according to claim 13, wherein said non-removed areas of said outermost layer have a surface resistivity lower than $10^6~\Omega/\text{square}$.
 - 15. Method according to claim 13, wherein said non-removed areas of said outermost layer have a surface resistivity lower than $10^4~\Omega/{\rm square}$.
- 16. Method of making an electroconductive pattern on a support without a removal step comprising the steps of:
 - providing a material for making an electroconductive pattern, said material comprising a support and a light-exposure differentiable element, characterized in that said light-exposure differentiable element comprises an outermost layer containing a polyanion and a polymer or copolymer of a substituted or unsubstituted thiophene having a surface resistivity lower than $10^6~\Omega/\text{square}$, and optionally a second layer contiguous with said outermost layer; and wherein said

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outermost layer and/or said optional second layer contains an aryl diazosulfonate according to formula (I):

$$MO_3S-N=N-Ar-L-Ar-N=N-SO_3M$$
 (I)

where Ar is a substituted or unsubstituted aryl group, L is a divalent linking group, and M is a cation; capable upon exposure of changing the removability of the exposed parts of said outermost layer relative to the unexposed parts of said outermost layer; and

- image-wise exposing the material thereby obtaining reduction in the conductivity of the exposed areas relative to non-exposed areas, optionally with a developer.
- 15 17. Method of making an electroconductive pattern on a support without a removal step according to claim 16, wherein said bis(aryldiazosulfonate) compound according to formula (I) is selected from the group consisting of

$$\begin{array}{c} CH_3 \\ O = S - OH \\ N \\ N \\ N \end{array}$$

$$\begin{array}{c} O = S \\ N \\ N \end{array}$$

$$\begin{array}{c} O = S \\ N \\ N \end{array}$$

$$\begin{array}{c} O = S \\ N \\ N \end{array}$$

$$\begin{array}{c} O = S \\ N \\ N \end{array}$$

and